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IN THE UNITED ST SES PATENT AND TRADEMARK OFFICE

Applicant(s):

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MEHDI

Assignee:

KLA-TENCOR TECHNOLOGIES CORPORATION

Title:

SYSTEM AND METHODS FOR A WAFER INSPECTION SYSTE

USING MULTIPLE ANGLES AND MULTIPLE WAVELENGTH

ILLUMINATION

Application No.:

Filing Date:

June 26, 2001

Examiner:

Hao Q. Pham

Group Art Unit:

2877

Docket No.:

M-10693 US

COMMISSIONER FOR PATENTS

Washington, D.C. 20231

INFORMATION DISCLOSURE STATEMENT

Dear Sir:

Pursuant to 37 C.F.R. § § 1.56, 1.97 and 1.98, Applicants wish to call the documents listed on the enclosed Form PTO-1449 to the Examiner's attention for the above-identified patent application. Copies of the listed documents are enclosed.

Citation of the above documents shall not be construed as:

1. an admission that the documents are necessarily prior art with respect to the instant

invention; or

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2. an admission that the information cited herein is, or is considered to be, material to

patentability as defined in § 1.56(b).

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Please charge the § 1.17(p) fee of \$180.00 against Deposit Account No. 19-2386. The

Commissioner is further authorized to charge any additional fee required, or credit any over

payment, to this Deposit Account. This paper is submitted in duplicate.

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Application No. 09/298,007

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